

1 RESULTS AND DISCUSSION:

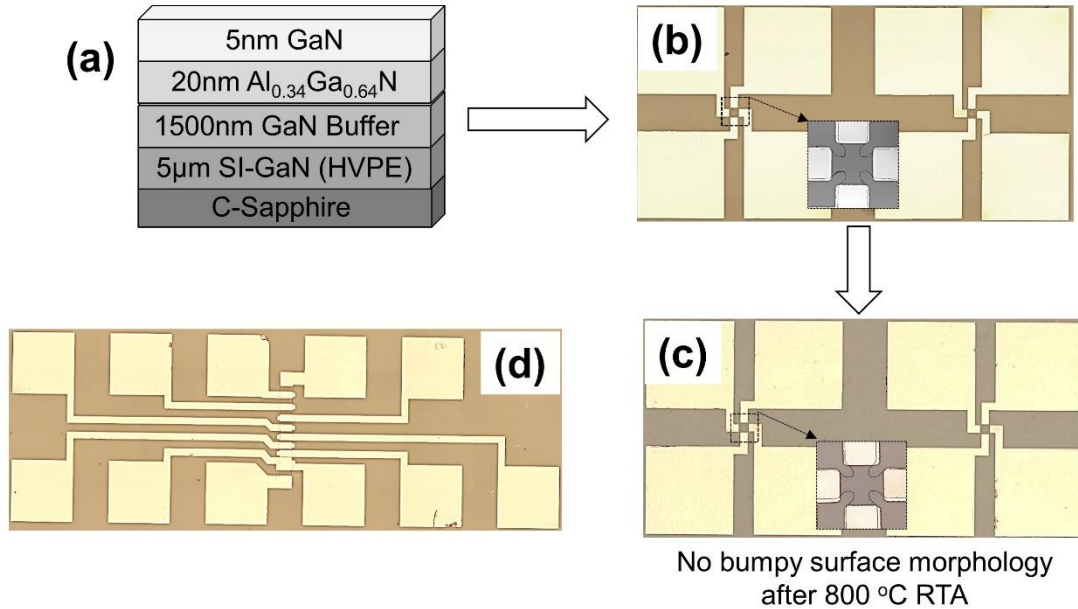
2 The $\text{Al}_{0.34}\text{Ga}_{0.66}\text{N}/\text{GaN}$ microfabricated Hall sensor [**Fig. 1(b)**], where evaluation of the 2-
3 DEG is achieved by investigating the Hall voltage which has direct influence on drift velocity of
4 carrier, as a function of thermal aging time. Fabricated Micro-Hall sensor sensitivity tested under
5 constant current and voltage bias mode for all thermal annealing protocol, corresponding data
6 presented in **Fig. 2(a & b)**. The efficiency of $\text{Al}_{0.34}\text{Ga}_{0.66}\text{N}/\text{GaN}$ micro-Hall sensor under thermal
7 aging, we calculated the Absolute Sensitivity (S_A), of a Hall device is defined as the change in
8 output Hall voltage (V_H) divided by the change in applied magnetic field (H) i.e., $S_A =$
9 $G_H \frac{r_H}{qN_{2\text{deg}}} I_b - - (1)$. Similarly, Supply Current Related Sensitivity (S_{scrs}) expressed as $S_{\text{scrs}} =$
10 $G_H \frac{r_H}{qN_{2\text{deg}}} - - (2)$, and Supply Voltage Related Sensitivity (S_{svrs}) can be defined as $S_{\text{svrs}} =$
11 $G_H \frac{r_H}{RqN_{2\text{deg}}} - - (3)$ which implies that $S_{\text{svrs}} = \mu_H G_H \left(\frac{L}{W}\right) - - (4)$. From above relation, it is
12 clear that current-related sensitivity (S_{scrs}) is inversely proportional to (n_s) and the voltage-related
13 sensitivity (S_{svrs}) is directly proportional to electron mobility. The measured taken current-related
14 sensitivity (S_{scrs}) were found to be $74 \text{ VA}^{-1}\text{T}^{-1}$ and $82 \text{ VA}^{-1}\text{T}^{-1}$ (SCRS), and voltage-related
15 sensitivity (S_{svrs}) are measured to be 0.053 T^{-1} and 0.051 T^{-1} (SVRS) for pristine sample and
16 after 2800 hours thermal aging at $200 \text{ }^\circ\text{C}$ in air. As we seen from **Fig. 2** there will be $\sim 2\%$
17 improvement in SCRS and $\sim 2\%$ change in SVRS of the Hall sensor after a prolonged baking times
18 of 2800 hours at $200 \text{ }^\circ\text{C}$. As expected, the Hall sensor has the ability to survive at $200 \text{ }^\circ\text{C}$ in air for
19 an extended period of time. The slight increasing trend of SCRS and decreasing trend of SVRS
20 with heating due to the combined changes in sheet carrier density and mobility ($n_s\mu$).

21 CONCLUSIONS:

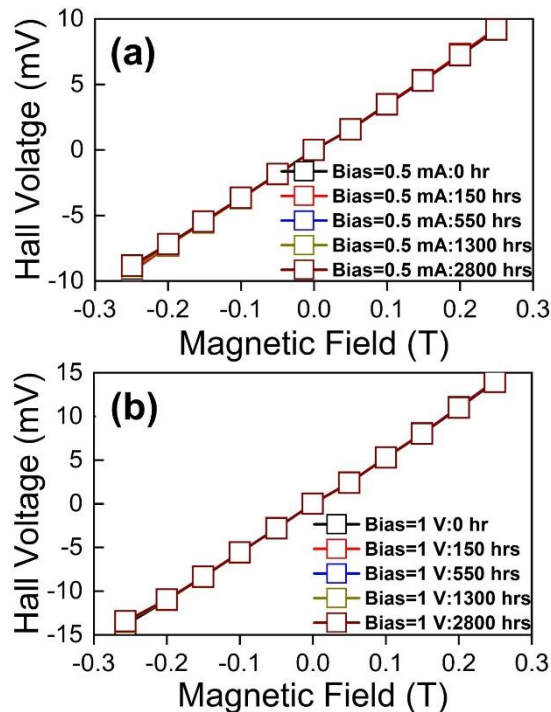
22 We have investigated the temperature response of $\text{Al}_{0.34}\text{Ga}_{0.67}\text{N}/\text{GaN}$ Hall sensors, in terms
23 of the Hall sensitivity, and Ohmic contacts during thermal aging at $200 \text{ }^\circ\text{C}$ for up to 2800 hours
24 under atmospheric conditions. The MBE grown $\text{Al}_{0.34}\text{Ga}_{0.67}\text{N}/\text{GaN}$ Hall sensors were
25 characterized by using HR-XRD, micro-Raman, and XPS on Hall sensor device before and after
26 thermal aging time. To compare the performance of the Hall sensor we have correlated the
27 structural evolution in $\text{Al}_{0.34}\text{Ga}_{0.67}\text{N}/\text{GaN}$ Hall sensor heterostructures with measured electric
28 response of Hall device. Results indicate that the $\text{Al}_{0.34}\text{Ga}_{0.67}\text{N}/\text{GaN}$ Hall sensor provides stable
29 performance for as long as 2800 hours aging at $200 \text{ }^\circ\text{C}$ without any significant degradation to the
30 sensitivity, and Ohmic contacts. However, this study conducted for Hall sensor device does not
31 have surface passivation, though we have noticed the out-diffusion of ‘Ga’ and ‘Al’ does not affect
32 much on performance of the Hall sensor. Addition we have found initial stage of contacts
33 resistance droop which could be due to out ‘Ga’ or Al diffusion process may be consequence of a
34 reduction of oxygen concentration at the GaN/Ti interface resulting in a reduced contacts barrier
35 height. The ‘Pt’ based ohmic contact enables bumpy free surface morphology after 800°C RTA.

36

1 **FIGURES:**



2
 3 **Fig. 1.** (a) Cross-sectional growth diagram of AlGaIn/GaN Hall sensor, (b) Plan view of Greek-
 4 Cross Hall sensor device before RTA, (c) Plan view of Greek-Cross Hall sensor device after Ohmic
 5 contact after RTA annealing (d) TLM structure used for contact resistance measurement.



6
 7 **Fig. 2.** Measured (a-b) Micro-Hall sensor have a linear response to magnetic field, both in current
 8 and voltage bias mode over a wide range of thermal annealing time at 200 °C in atmospheric
 9 condition.